



Building the electrical model of the Photoelectric Laser Stimulation of a PMOS transistor in 90 nm technology

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Purpose

- **Understand effect of PLS (Photoelectrical Laser Stimulation) on a diode and then on a PMOS transistor in 90nm technology.**
- **Present an electrical model of a PMOS transistor under PLS.**



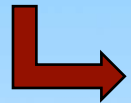
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Introduction:

- ❑ Failure analysis: extensive use of laser stimulation techniques:
Extensive and **time consuming**

- ❑ This paper present:



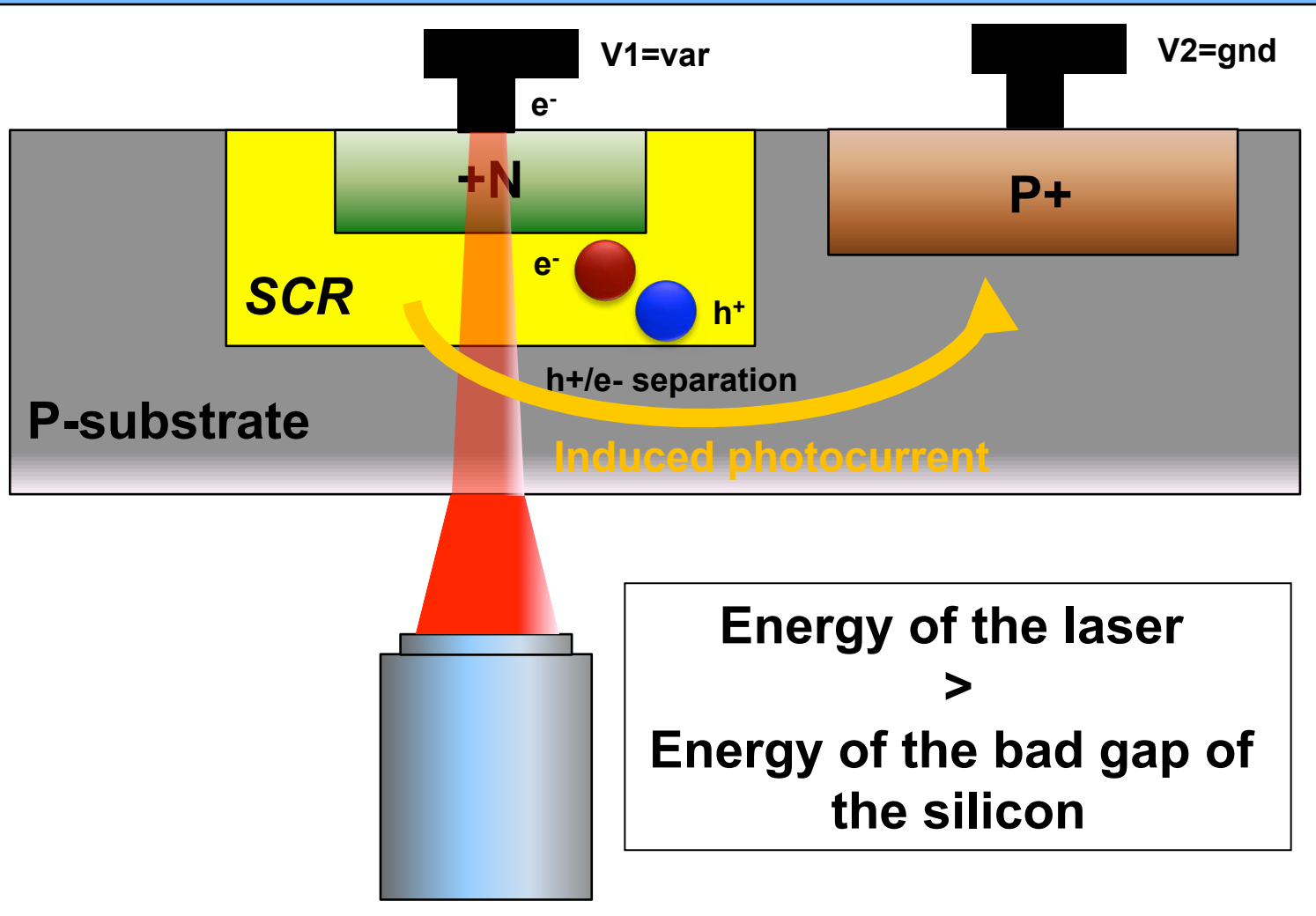
an electrical model of the PLS of a PMOS transistor.



Build from: electrical measurements (I-phemos Hamamatsu)

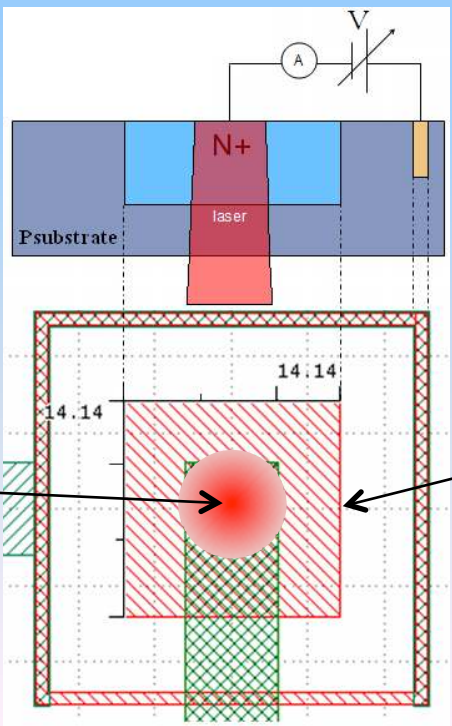
Goal: Predict the response of a PMOS transistor to PLS in a very small amount of calculation time.

Principle of the Photoelectric Laser stimulation (PLS)



Characterization of a diode N+ on P-substrate under PLS

Laser parameter	Value
Continuous laser beam	Yes
Laser power	Variable from 0 to 40 mw
Diameter of the spot	Ø 3.25 µm
Laser wavelength	1064 nm



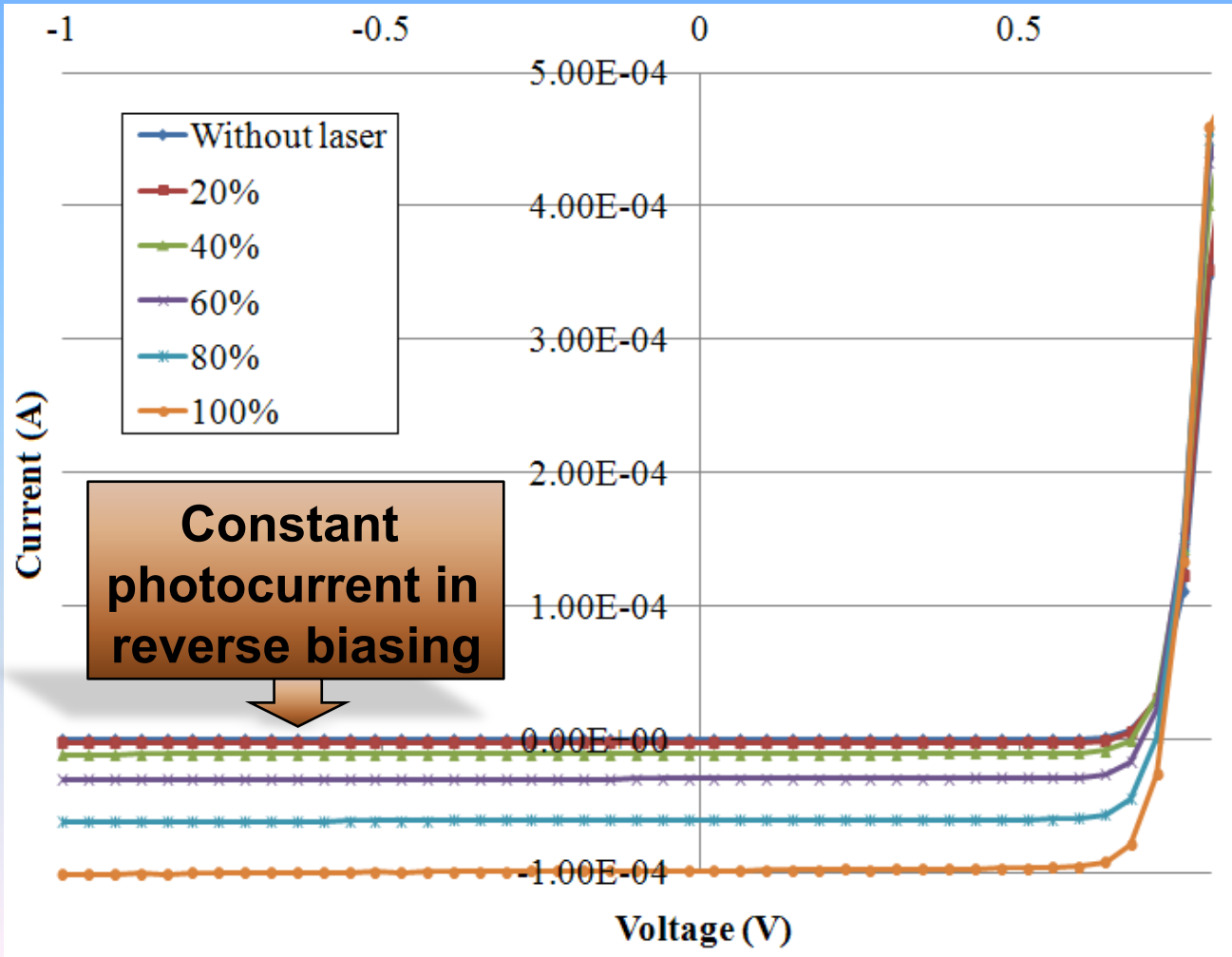
Localization of the laser beam

Layout of the diode N+ on P-substrate

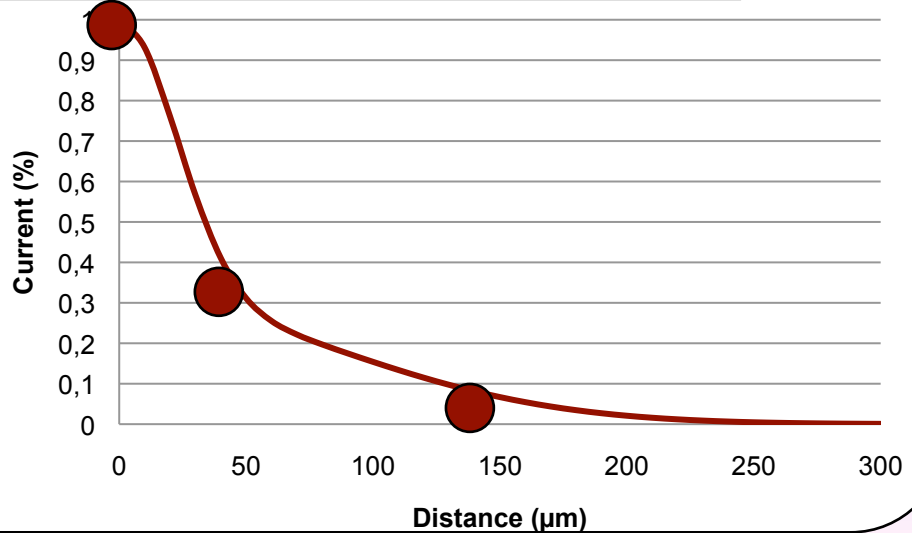
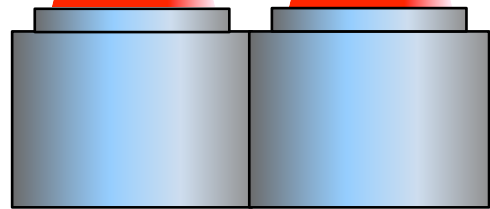
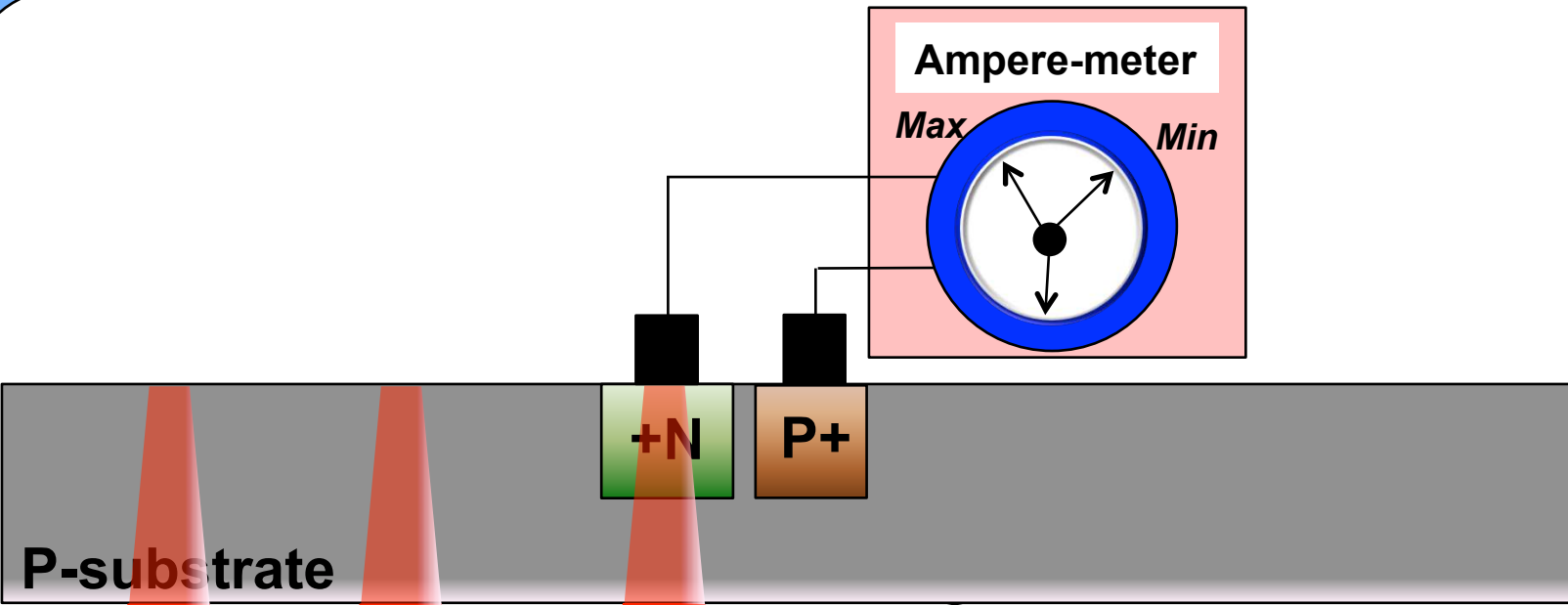


Measurement of a diode under PLS

I(V) characteristic of a N+/P-substrate diode under PLS



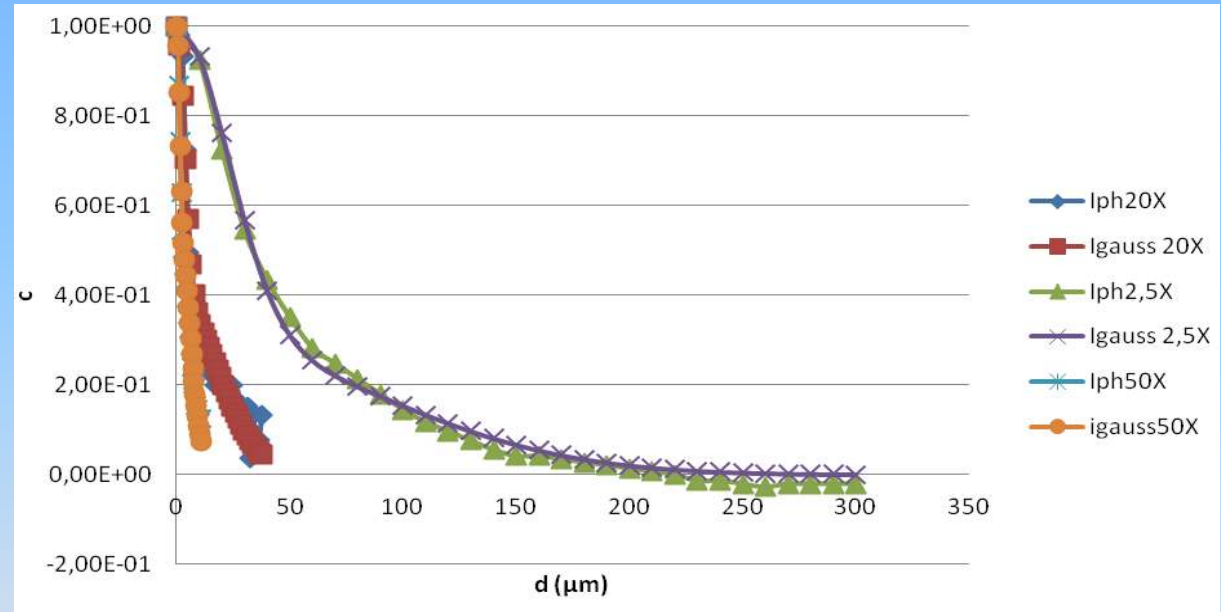
Gaussian effect on a PN junction





Gaussian like behavior of the N+/ Psubstrate diode

Characterization made for the three objectives of the I-phemos equipment 2.5X – 20X – 50X



Extracted from measurement

$$\alpha_{gauss}(d) = a * \exp\left(-\frac{d^2}{c_1}\right) + b * \exp\left(-\frac{d^2}{c_2}\right)$$

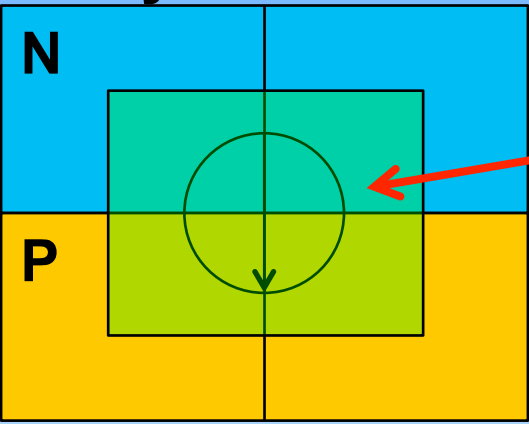
Same methodology for the Nwell/Psubstrate diode

	2.5X	20X	50X
a	0.4	0.6	0.7
b	0.6	0.4	0.3
c ₁	2.5	23.8	1000
c ₂	55	654	15000

	2.5X	20X	50X
a	0.5	0.6	0.7
b	0.5	0.4	0.3
c ₁	2	1000	1500
c ₂	48	15000	17000

Presentation of the subckt Iph

In our model every PN junction under PLS are modeled by a current source



Subckt Iph
Iph_val

$$Iph_val = S * I_{laser} * \alpha_{gauss}$$

Where: **S** is the area of the PN junction

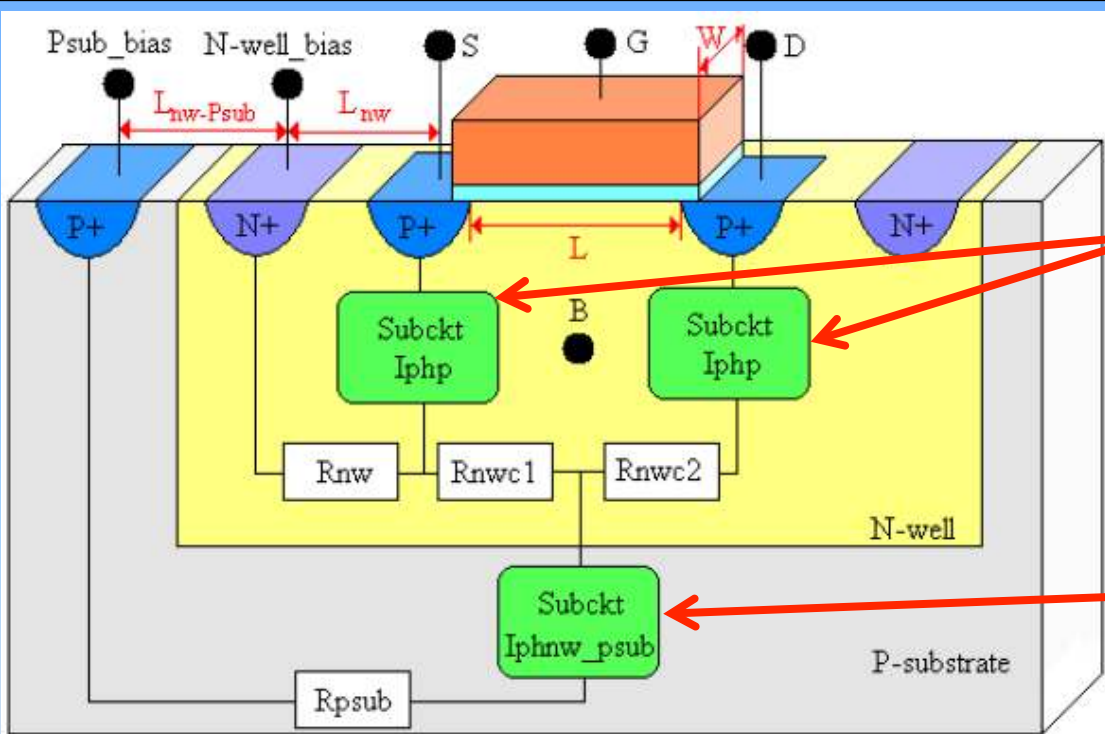
I_{laser} is a function depending of the laser power **P_{laser}**

$$I_{laser} = 0.0323 * P_{laser}^2 + 0.3335 * P_{laser} - 0.1624$$

Alpha_{gauss} is a parameter evolved between **0** and **1**

$$\alpha_{gauss}(d) = a * \exp\left(-\frac{d^2}{c_1}\right) + b * \exp\left(-\frac{d^2}{c_2}\right)$$

Presentation of the electrical model



2 Subckt Iph

2 Subckt Iphnw_psub

For every PN junction the user have to plug a subckt Iph and set two parameters:

- The area of the PN junction: S
- The distance between the laser spot and the closest edge to the junction: d

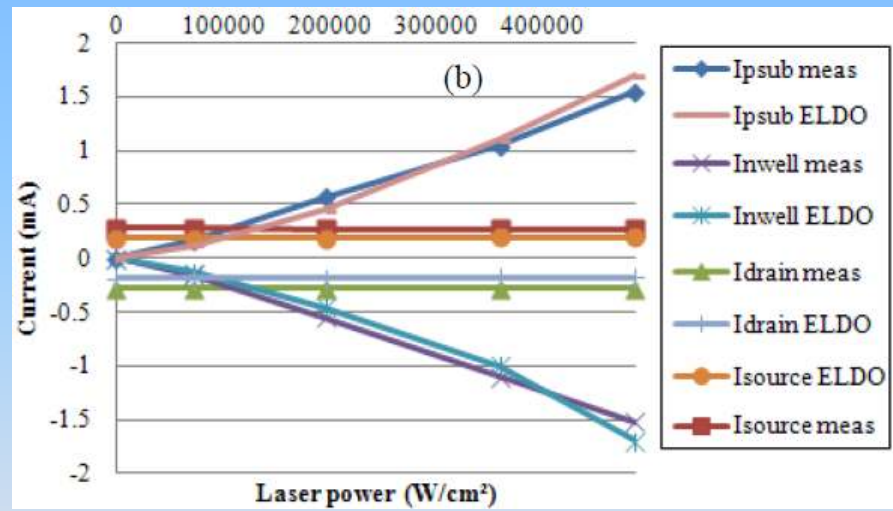
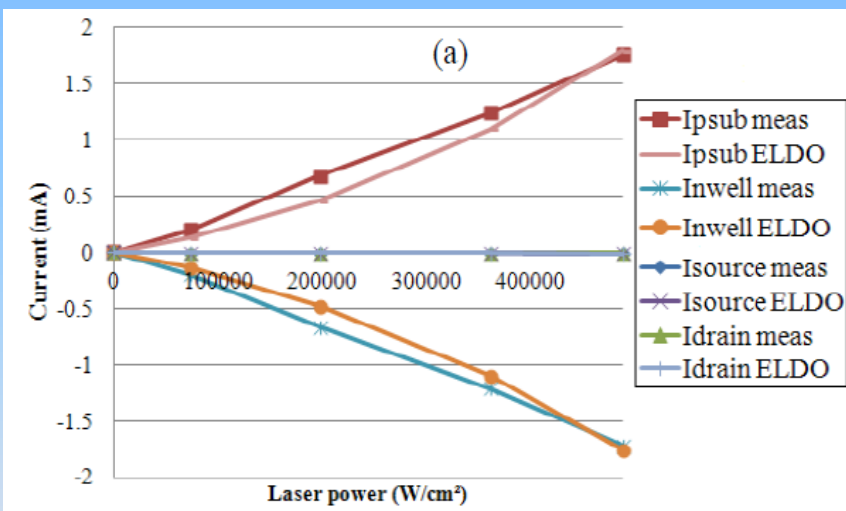


Laser power ELDO simulation vs measurement

PMOS transistor

W=10μm/L=0.09μm
Turn OFF

W=10μm/L=1.2μm
Turn OFF



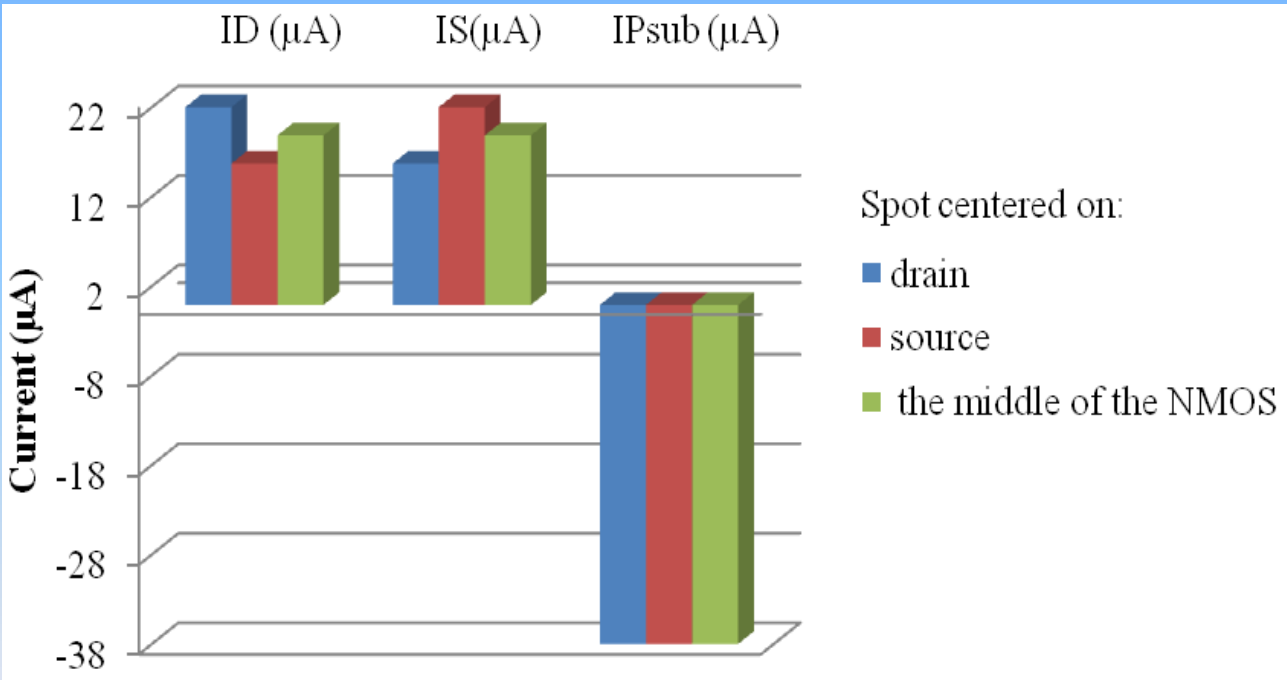
$$|I_{substrate}| = I_{drain} + I_{source}$$

Good correlation between ELDO simulation and measurement

Current cartographies

Principe

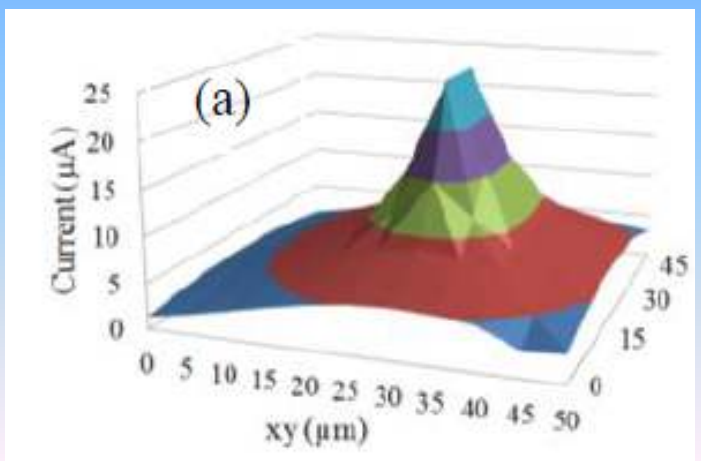
Extracted from ELDO simulation



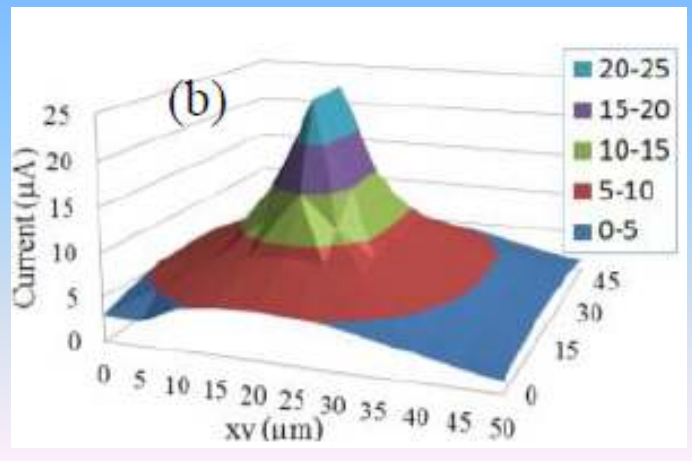
More the spot is close to the PN junction and more its photocurrent is high.

3D current cartographies extracted from ELDO simulation

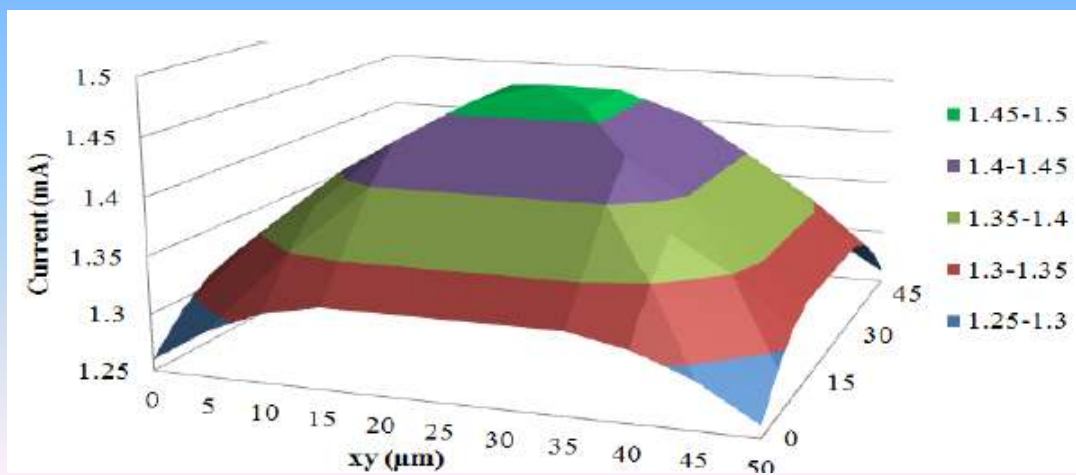
From drain electrode



From source electrode



From P-substrate electrode





Conclusion

- **Electrical simulation of the interaction between laser and silicon on a PMOS transistor in 90nm technology seems to be an extremely reliable, fast and also economical tool**
- **The validity of our approach is assessed by the very good correlation obtained between simulations and measurements.**
- **This work will be extended to PMOS transistors and then more complex gates.**



Thank you for your attention...